

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 241584US0CONT		SERIAL NO. 10/642,618 New Application	
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT					
		Hideaki SAKURAI, et al.					
		FILING DATE Herewith 8-19-03		GROUP		2813	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
<i>DS</i>	AA	5,891,531	01-1999	KONISHI, ET AL.	—		
	AB	5,496,583	03-1996	JANSEN, ET AL.	—		
<i>↓</i>	AC	5,462,922	10-1995	DOI, ET AL.	—		

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION
					YES NO
<i>JK</i>	AD	2001-035382A	02-2001	JAPAN	
	AE	2000-331601A	11-2000	JAPAN	
	AF	41049767A	06-1998	JAPAN	
	AG	96/19825	06-1996	WIPO (corresponding to JP 10-512100)	
	AH	10-512100	11-1998	JAPAN (w/English Abstract)	
	AI	10-149767	06-1998	JAPAN (w/English Abstract)	
	AJ	2741546	01-1998	JAPAN (w/English Abstract)	
	AK	87-01508	03-1987	WIPO (corresponding to JP 6-26206)	
	AL	6-26206	04-1994	JAPAN (w/English Abstract)	
	AM	10-101830	04-1998	JAPAN (w/English Abstract)	
	AN	10-204195	08-1998	JAPAN (w/English Abstract)	
	AO	09-040881	02-1997	JAPAN (w/English Abstract)	
<i>✓</i>	AP	10-182861	07-1998	JAPAN (w/English Abstract)	

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

<i>DS</i>	AQ	Vossen, John L., "Thin Film Process", Academic Press, 1978, Pages 438-439.
<i>DS</i>	AR	H., Seehase, "Plasma Display Panel MgO Thin Film Properties and Their Modification by Low Energy Ion Bombardment", Displays, January 1985, Pages 21-34.
	AS	Monthly Semiconductor World, [3], 1998, Pages 121-123.
	AT	Excalibur Paper Phase Cleaning System Described in the Catalog of MFSI Co., Ltd.
	AU	FALCON HF Reduced Pressure Gas Phase Etching System Described in the Catalog of ASM Japan Co., Ltd.
	AV	M.N. Abraham, et al., "Growth of High Purity and Doped Alkaline Earth Oxides: I. MGO and CaO", The Journal of Chemical Physics, 35[8], 1971, Pages 3752-3756.
	AW	"The Latest Plasma Display Manufacturing Technology", Press Journal, Inc. December 1, 1997.
	AX	Lee, W.T., "Study of Protective Layers in AC-PDPs", IDW 99, Pages 763-766.
	AY	"Preparation of MgO Protective Films for Plasma Display Panels Using Vacuum Deposition Methods", ULVAC Technical Journal, No. 46, 1997, Pages 8-13.
<i>✓</i>	AZ	"Cathode Materials for Color Plasma Displays", O Plus E, February 1996.
		<input type="checkbox"/> Additional References sheet(s) attached
Examiner	<i>DS</i>	Date Considered 11/21/04

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.